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Instruments and Technology*

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## **Optoelectronic Measurement Technology and Systems**

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*Editors*

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## Introduction

With the deepening and intensification of social informatization, a wider range of information sources and acquisition methods have become the basis for social development. Because of its large capacity, high efficiency and high precision, optoelectronic measurement technology has become the main means of information sensing and acquisition. It has played – and will continue to play– an significant role in important fields such as: consumer electronics, industrial manufacturing, environmental protection, and scientific research.

Optoelectronic measurement research covers a rich content, including many of areas from scientific research to manufacturing industry for our daily life. The scope will expand continuously and the content to become more and more deep as research goes further. On one hand, the traditional optoelectronic measurement research and applications (represented by the background of industrial measurement and optoelectronic detection) have been constantly improved, and the relevant performances have continuously improved as well. On the other hand, the needs of optoelectronic measurement (represented by the spectral measurement and optical dynamic measurement) have continued to emerge, as well as the measuring methods and applications that have been developed.

More than 80 papers (4 invited and 22 oral) have been accepted into the OIT 2017: Optoelectronic Measurement Technology and Systems conference proceedings. They span many research fields including: optoelectronic measurement, optical instruments, industrial measurement, spectral measurement, optical dynamic measurement, etc. These papers appropriately reflect the current focusing problems and research level of the optoelectronic measurement field.

**Jigui Zhu**  
**Kexin Xu**  
**Hwa-Yaw Ta**  
**Hai Xiao**



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